

IONIZED JET DEPOSITION

NOVEL THIN FILM COATING TECHNOLOGY

HIGH DEPOSITION RATES

STOICHIOMETRY CONSERVATION

LAB SCALE / R&D / INDUSTRIAL

INDEPENDENT PROCESS
TUNING PARAMETERS

LOW TEMPERATURE PROCESS

WIDE RANGE OF MATERIALS

HIGH QUALITY COATINGS

COMPETITIVE COST





LAB JET40 - SMALL R&D DEPOSITION SYSTEM

Multi-purpose configuration:

125 I Chamber

1 IJD source

Optional addons:

magnetron laser window

thermal evaporation

electron beam ev.

heated sample holder carousel

etc.



MEDIUM SIZE R&D DEPOSITION SYSTEMS





LAB JET 6.0

240 I Chamber

LAB JET 8.0

460 I Chamber

Up to 5 IJD heads + optional addons: magnetron sputtering, laser window, thermal evaporation, electron beam evaporation, heated sample holder, carousel, etc.

